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semiconductor performance





at surface mount speeds

Building Better

System-level solutions for next-generation challenges

Bringing high productivity to advanced packaging assembly

Traditional advanced assembly methods can no longer keep pace with today's higher-volume, higher-complexity production demands. Universal's FuzionSC™ Platform offers a complete solution to today's most challenging semiconductor packaging applications by combining extreme accuracy with surface mount performance. FuzionSC is the ideal solution for Flip Chip, System-in-Package (SiP), 2.5D, Package-on-Package (PoP), Wafer and Panel-level Fan-out, Embedded, and Conformal Shielding applications.

With the largest component range of any advanced packaging pick-and-place solution, FuzionSC has the inherent capability to assemble a complete module on a single machine, placing both die and passives precisely and seamlessly. This enables you to move quickly and cost-effectively to your next product while getting to market faster, minimizing operating costs and enjoying long-term asset protection.





Empowered by know-how

Universal Instruments' solutions include not only best-in-class equipment, but also proven in-depth process knowledge, application expertise and integration experience to ensure your equipment delivers your product at the highest possible yield and reliability, and at the lowest possible cost.

- ±10µm accuracy, < 3µm placement repeatability • High throughput up to 10K cph Advanced Packaging Assembly Solutions (APAS), 30K cph standard applications • Populate the largest panels to process higher die counts

All-in-one platform for any assembly challenge

- Place broad range of die and components on one platform Placement capability from ANY feeding option
- Place on ANY substrate

Leverage process expertise and years of experience

- introduction, maximizing yield and optimizing reliability
- Advanced Process Lab focused on realizing rapid product • APAS applications since 1990; thousands of platforms, all markets







Achieve best accuracy at highest speed over largest area

New Benchmark





±10μm accuracy, < 3μm placement repeatability

- High-stiffness frame, within 1µm from corner to corner
- Proprietary VRM linear motor: thermally stable, dual-drive, 1µm resolution
- Optimized motion control for sub-micron repeatability
- Environmental thermal management
- High-resolution optics, mapping and calibration routines
- Two-step precise global fiducial find
- Look before pick
- Top Alignment Process (TAP)
- Accuracy Management System (AMS) validates accuracy while in production
- AOI feedback and placement adjustment

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		Station Contraction of the second

300mm ~71K mm²

625mm x 813mm ~508K mm²

High throughput up to 10K cph APAS, 30K cph standard applications

- Dual-drive VRM linear motor with fast motion response and settling times
- Available dual-beam configurations with multiple heads
- Multiple heads/spindles reduces number of cycles from pick to place
- Gang pick and gang dip maximizes cycle time efficiency
- On-the-fly vision with large field of view

Populate the largest panels to process higher die counts

- Traditional platforms follows wafer form factor, limiting assembly size
- Populate panels without sacrificing speed or accuracy
- Achieve a 7X processing increase!



All-in-one platform for any assembly challenge

Place broad range of die and components on one platform

- High-accuracy flip chip, bare die, surface mount, and odd-form
- Full range of die: 0.5–40mm, 0.05–4mm thick
- Advanced vision algorithms, programmable lighting, bump recognition down to 20µm
- SMT: 01005–55mm square and up to 25mm tall
- Supports solder/flux dipping and pin transfer
- 150–5000g placement force (lower-force options available), dynamic force control

Placement capability from ANY feeding option

- Wafer, tray, tape, tube, and bulk
- Supports wafers up to 300mm and multiple die part numbers
- Tape: 4 x 1mm (01005) up to 56mm
- Matrix tray: supports stationary and automated stackable feeders (2x2, 4x4, JEDEC)





All-Around Performer







Place on ANY substrate

- Thin, thick, narrow, and large assembly area
- Substrates, wafers, lead frames, ceramics, glass, flex, and laminates
- Reel-to-reel systems

Differentiation Through Knowledge

Leverage process expertise and years of experience

Advanced Process Lab focused on realizing rapid product introduction, maximizing yield and

optimizing reliability

- Leading-edge, fully equipped laboratory
- Optimized assembly solutions (design, materials, process, pioneering equipment technology)

for new and existing products

- Prototyping and development, first article build, NPI, volume production
- Design for Manufacture (DfM), Design for Reliability (DfR)
- Research partnerships: industry-leading Consortium, multiple University collaborations

APAS applications since 1990; thousands of platforms, all markets

- Flip Chip in Package
- System-in-Package
- Wafer-Level Packaging
- Embedded
- High-Accuracy Place
- High-Speed Passive







One solution for all advanced packaging application challenges

The precision performance and versatile capabilities of the FuzionSC deliver maximum throughput per floor space for virtually any application. With an unbeatable combination of speed, accuracy and flexibility, FuzionSC will have you well-positioned for your next product.





pass-down

Flip Chip in Package

- Substrate and carrier handling with precision lifter and vacuum tooling
- Film Applicator (LTFA)
- Supports up to 4 Innova direct die feeders for multi-die applications • High-speed passive/SMT device
- placement
- Vision algorithms/lighting support all substrate materials & packages
- Look-before-pick ensures highest pick accuracy







Embedded

- Best accuracy (±10µm) at highest speed over largest area
- Panels up to 610mm x 813mm
- Supports high device count, both passives and actives
- AOI accuracy feedback for post-process compensation Precision material handling and
- thermal stage options
- Die-level traceability SECS-GEM
- Top-side alignment (TAP) process



High-Accuracy Place

- - High speed, high accuracy • 01005–55mm sq & up to 25mm tall Top-side alignment (TAP) process for LED headlamps, CPV Advanced vision algorithms,

 - programmable 3-axis lighting
 - Wafer, tray, tape, tube, and bulk feeding formats
 - Custom applications tooling: • Up to 5000g force, 30 seconds
- dwell



- Flux dip capability with Linear Thin

All Markets



 Thin and narrow substrate handling Bad circuit detection, electronic

• Gang flux dip for maximum cph • Supports up to 4 Innova direct die feeders for multi-die applications • High-density passive placement,

- 01005 and smaller, 4x1 feeding
- Small fiducial & fiducial teach-by-
- show pattern find
- Highest speed flip chip placement



nozzles, grippers, substrate support



Wafer-Level Packaging

- Best accuracy (±10µm) at highest speed over largest area
- Supports panels up to 610mm x 813mm
- AOI accuracy feedback for post-process compensation
- Software supports high die count assemblies
- Precision material handling and thermal stage options
- Die-level traceability SECS-GEM



High-Speed Passive

- Available dual-beam configurations with multiple heads
- Up to 14 spindles with gang pick
- Up to 30,750 cph
- 4 x 1mm tape feeders
- High-speed & high-accuracy modes
- Bad circuit detection, electronic pass-down
- Custom applications tooling: nozzles, substrate support
- Motion profiles for sensitive device handling



FuzionSC Portfolio & Solutions







FuzionSC2-14

For higher throughput requirements

	Dual-beam, dual-drive overhead gantry system
	2 FZ7 (7-spindle) placement heads
	450ms tact time (w/ flux dipping), 360ms (w/out)
	FuzionSC2-14 Specifications
Throughput (cph)	30,750 (Max) / 14,200 (4-Bd IPC Chips)
Accuracy (µm@>1.00 Cpk)	±10 (Array Devices/Flip Chip) / ±38 (Passives/Chips)
Max Board Size	508 x 813mm (20 x 32"), larger board specials available
Max Feeder Inputs (8mm)	120 (2 ULC)
Feeder Inputs Types	Wafer (up to 300mm), tray, tape, tube, and bulk
Component Range (mm)	(0201) .25 x .5 x .15 (Min) to 150 square (MFoV), up to 25 tall
Min Bump Size & Pitch (µm)	Bump Size: 20, Bump Pitch: 40

Scalable solutions for cost-efficient productivity

Stand-alone machine solution – All-in-one efficiency

Single-beam for high flexibility, dual-beam for higher throughput; Wafer, tray, tape, tube, bulk feeding - Fan-Out WLP, Die Attach, Lid Attach, High-Accuracy Place, Embedded

Throu

Mass reflow – Full-process, high-mix/NPI

Complete process solution supporting multiple feeding formats and flux or solder paste dipping - Package-on-Package, System-in-Package, 2.5D, Flip Chip, SMT, Odd-Form

Mass Reflow – Scaled assembly, Medium-mix, medium-volume

Complete process solution with dedicated chip placer and flexible high-accuracy placer supporting HVHM tray packaging – High-Speed Passive, High-Accuracy Flip Chip

Mass Reflow – Medium to high-volume

Complete process solution with chip placer and high-accuracy placer; higher volume, same footprint – System-in-Package, High-Speed Passive, High-Accuracy Flip Chip

Mass Reflow – Versatile high-volume

High-throughput full process solution with large feeder capacity for streamlined changeovers – System-in-Package, High-Speed Passive, High-Accuracy Flip Chips, WLP



FuzionSC1-11

uzionSC1-11 PT

zion2-60 EuzionSC2-14

Fuzion4-120

Fuzion4-120 FuzionSC2-14 PTF

Lower cost with additional flexibility

Single-beam, dual-drive overhead gantry system
1 FZ7 (7-spindle) + 1 optional FZ4 (4-spindle) placement head
750ms tact time (w/ flux dipping), 600ms (w/out)
FuzionSCI-11 Specifications
16,500 (Max) / 8,400 (4-Bd IPC Chips)
±10 (Array Devices/Flip Chip) / ±38 (Passives/Chips)
508 x 813mm (20 x 32"), larger board specials available
120 (2 ULC)
Wafer (up to 300mm), tray, tape, tube, and bulk
(0201) .25 x .5 x .15 (Min) to 150 square (MFoV), up to 25 tall
Bump Size: 20, Bump Pitch: 40

Advanced technologies for advanced applications

FuzionSC features specialized technologies to address leading-edge component packaging challenges.



VRM Linear Motor Positioning System



- High-accuracy (1µm resolution), closed-loop positioning
- control supports converging & emerging technologies
- High acceleration (up to 2.5G), thermally stable
- Self-correcting, dual-drive control reduces settle times

Accurate, flexible FZ[™] placement heads

Precision accuracy (27µm (a) Cpk>1)

- 0201 150mm square (MFoV), up to 25mm tall
- High-speed IC and chip, gang pick up to 7 components
- Standard Package-on-Package (PoP) functionality

Multiple feeding options for flip chip, bare die, SM



- Up to 4 direct die feeders, wafers up to 300mm
- Stationary and stackable matrix trays
- Standard and dual-lane tape for small passives

High-resolution Magellan digital cameras



- Supports all flip chip and SM devices • High resolution of 1024 x 1024 enables small part feature recognition
- 2.3, 0.94, 0.5, 0.2MPP (supports 20µm bumps/pillars)





Capability Designed In





Fast, precise PEC Camera

- High-resolution (.27MPP)
- Programmable lighting, wavelength illumination, cross polarization
- Standard/taught fiducial and pad site recognition



Advanced vision algorithms & lighting

- Front, side, and on-axis combination lighting
- Lighting calibration performed on the machine,
- eliminating machine-to-machine intensity variation
- Lighting intensity is consistent across viewable area



Precision lifter & tooling

- Handles strips/lead frame, auer boats, carriers/pallets, boards/panels from 0.10mm – 12.0mm thick
- Integral vacuum generator
- Precise registration of the substrate in x, y and z axis

Versatile substrate handling



- Thin, thick, narrow, and large assembly area
- Substrates, wafers, lead frames, ceramics, glass, flex, and laminates
- Large substrates up to 625mm x 813mm



Complete Solutions



Linear Thin Film Applicator (LTFA)

On-board dipping for maximum efficiency

The Linear Thin Film Applicator (LTFA) creates a thin film of flux, solder paste, or adhesive. Flip chips, stacked CSPs and other area array packages are individually or gang dipped, thereby applying the necessary amount of material to the appropriate area.

• Linear actuation for thickness uniformity and repeatability

- Gang dipping, up to seven spindles
- Up to two LTFAs per FuzionSC Platform
- Quick-change plates for depth control (no adjustments)
- Typical viscosity 10K 28.5K centipoise
- Programmable milling cycles
- Programmable dipping dwell time
- Programmable Maintenance Monitor
- Quick-release tooling for easy cleaning
- Large reservoir (up to eight hours run time)
- Dip verification based on spindle impact sensing

Accuracy Management System (AMS)

Maintaining the performance you demand

The Accuracy Management System (AMS) combines a hardware station with supporting

software to manage FuzionSC accuracy performance over time.

- Uses patterned glass plate and glass device to measure and automatically optimize placement accuracy
- Aligns each individual spindle in x, y and theta
- Ensures sub-micron process repeatability
- User interface displays X, Y offset history
- Activated by time/board number intervals or temperature limits



Innova Direct Die Feeder

Delivering high-speed bare die to the mainstream

Embrace the convergence era of electronics assembly with the Innova[™] and Innova +[™] Direct Die Feeders. Innova enables the presentation of wafer-level devices to Universal's FuzionSC

Platform without incurring costly packaging charges.

- Presents flip chips and bare die in wafer format for pick and place
- Enables flip chip, bare die and SMT on a single platform
- Single-wafer feed (Innova), 13-slot cassette wafer-feed (Innova +)
- Eliminates upstream wafer sorting
- Ideal for SiP applications
- Up to four feeders per FuzionSC Platform
- Processes wafers up to 300mm
- Ink and ink-less wafer map support
- Wafer expansion: programmable (Innova +), fixed with grip rings (Innova)
- Flip and non-flip die presentation support
- Traceability support
- Ideal for NPI or high-volume

Ensuring highest accuracy without compromise

- Field-retrofittable option







Complementary Technologies





	Innova Direct Die Feeder Specifications
Max Throughput (uph)	Flip Chip: 4,700 for 1mm die Direct Chip: 4,000 for 1mm die
Presentation Accuracy (Cpk ~1)	X,Y = \pm 0.15mm (a) 3s / \pm 27.0° (verified against 1.0mm die size)
Wafer Specification	Maximum Size: 300mm (12") Minimum Size: 100mm (4") Expansion Depth: 6.35mm, 6.0mm, 0.0mm (unexpanded)
Vision Recognition Methods	Thresholding, Pattern Matching, Corner Detection, Solder Bump Detection, Wafer Mapping
Die Specification	Minimum Size (L x W): 0.7mm x 0.7mm (0.027" x 0.027") Maximum Size: (L x W) 11.0mm x 11.0mm (0.43" x 0.43") Minimum Thickness: 75 μm (0.003") Maximum Thickness: 4.0mm (0.163" nominal) Die Material: Silicon, Gallium Arsenide, Ceramic, Glass Ball Types: Ball bumps, Stud bumps

Precisor Top Feature Inspection Station

The Precisor[™] Top Feature Inspection Station optimizes placement

accuracy by providing a platform for precise device inspection.

- Provides accurate top-side feature alignment through
- body-to-feature inspection
- Leverages gang pick and place for speed
- Holds up to 7 components with vacuum

